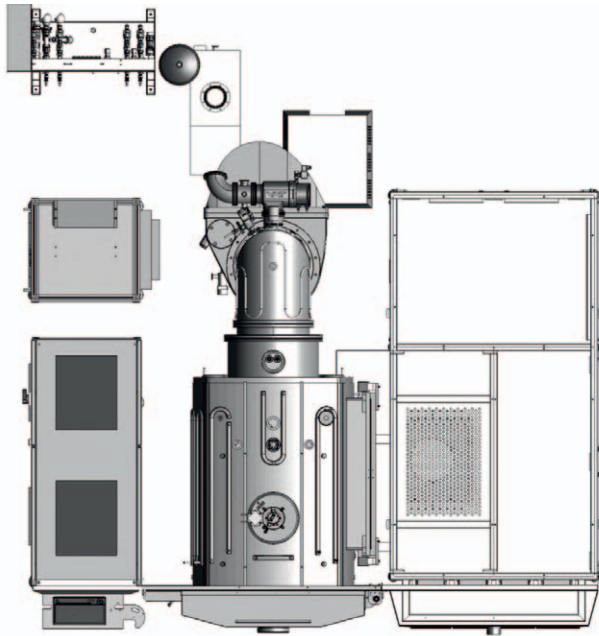


BAK AUTOLOAD

For superior wafer handling





With cassette to cassette handling for wafer sizes up to 8 inch, **BAK Autoload** completely eliminates manual handling of wafers saving time, eliminating operator errors and reducing costs. **BAK Autoload** takes care of all necessary steps including wafer alignment for flat or notch, preloading domes and complete dome exchange through a side port in the coater. Precise control of robot and handling environment avoids potential sources of damage or contamination. Full integration with Evatec's Khan process controller ensures seamless hardware management.

Complete process control

- Full tracking of wafer position in the coating dome for highest traceability and statistical process control
- Automatic recognition and handling of metrology or dummy wafers
- Integration of bespoke post-treatment modules
- Dome exchange typically less than 3 minutes

Substrate capacity chart

Wafer size	Dome Capacity
4"	42
6"	20
8"	9



About Evatec

Evatec offers complete solutions for thin film deposition and etch in the optical and semiconductor markets. Evatec engineers are able to offer practical production advice from R&D to prototyping and mass production. We recognize that no single technique offers the answer to all problems. With a technology portfolio including standard and enhanced evaporation as well as sputter, PECVD, and Plasma Etch we are ready to offer sampling services and custom engineering to meet our customers individual needs.

We provide sales and service through our global network of local offices. For more information visit us at www.evatecnet.com or contact our head office.

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